



# IUMRS-ICEM 2018

AUGUST 19(SUN.) - 24(FRI.), 2018 / DAEJEON, KOREA

<b>Session Title</b>	<b>Microelectronics Packaging Materials and Processing I</b>	<b>Session Code</b>	<b>Th-J1</b>
<b>Date and Time</b>	<b>2018-08-23 / 10:30 - 12:30</b>		
<b>Place</b>	<b>Room J</b>		
<b>Session Chair</b>	<b>TBA</b>		

Th-J1-1

10:30 - 11:00

### **[Invited] Power Device Bonding Technology for Electric Vehicle Applications**

Jeong-Won Yoon<sup>1,2</sup>

<sup>1</sup>KITECH, Korea, <sup>2</sup>Univ. of Sci. and Tech., Korea

Th-J1-2

11:00 - 11:30

### **[Invited] Thermo-Mechanical Characteristics of Solder Joints with Pillar Bump's Aspect Ratios**

Hee Seon Bang, Han-Sur Bang, and Hyeong-Cheol Kim  
Chosun Univ., Korea

Th-J1-3

11:30 - 11:45

### **Al-Ge Eutectic Bonding for MEMS: Managing The Presence of Native Oxide at the Interface**

Victor Lumineau<sup>1,2</sup>, Frank Fournel<sup>1,3</sup>, and Fiqiri Hodaj<sup>2</sup>

<sup>1</sup>LETI, France, <sup>2</sup>Univ. Grenoble Alpes, France

Th-J1-4

11:45 - 12:00

### **Characteristics of Hi Barrier Film using Polysilazane-Derived Silica Thin Films**

Sunmin Kim<sup>1,2</sup>, EunHae Koo<sup>2</sup>, and Daeho Yun<sup>1</sup>

<sup>1</sup>Sungkyunkwan Univ., Korea, <sup>2</sup>KICET, Korea

Th-J1-5

12:00 - 12:15

### **Development of New Analysis Method with Ultrasonication for Incoming PVA Brush in Post CMP Cleaning Process**

Jun-Kil Hwang<sup>1</sup>, Jung-Hwan Lee<sup>1</sup>, Muthukrishnan Purushothaman<sup>1</sup>, Kwang-Min Han<sup>1</sup>, Shohei Shima<sup>2</sup>, Satomi Hamada<sup>2</sup>, Hirokuni Hiyama<sup>2</sup>, and Jun-Goo Park<sup>1</sup>

<sup>1</sup>Hanyang Univ., Korea, <sup>2</sup>EBARA Corp., Japan